



SHEET 1 OF 1

Form PTO 1449  
(Modified)U.S. DEPARTMENT OF COMMERCE  
PATENT AND TRADEMARK OFFICE

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09/770,289

## LIST OF REFERENCES CITED BY APPLICANT

APPLICANT

Atsushi SHIOTA, et al.

FILING DATE

January 29, 2001

GROUP

1712

## U.S. PATENT DOCUMENTS

EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	FILING DATE IF APPROPRIATE
	AA						
	AB						
	AC						
	AD						
	AE						
	AF						
	AG						
	AH						
	AI						
	AJ						
	AK						
	AL						
	AM						
	AN						

## FOREIGN PATENT DOCUMENTS

		DOCUMENT NUMBER	DATE	COUNTRY	TRANSLATION	
					YES	NO
MF	AO	WO 99/36953	7/22/99	WIPO		
MF	AP	WO 97/00535	1/3/97	WIPO		
MF	AQ	EP 1 050 601	11/8/00	EP		
MF	AR	EP 0 921 561	6/9/99	EP		
	AS					
	AT					
	AU					
	AV					

## OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, etc.)

MF	AW	MCCLATCHIE, S. et al. "Low Dielectric Constant Oxide Films Deposited Using CVD Techniques", Dunic Conference Proceedings, February 1998, pages 311-318.				
	AX					
	AY					
	AZ					<input type="checkbox"/> Additional References sheet(s) attached

Examiner

Muel J. [Signature] 9/15/04

Date Considered

9/15/04

\*Examiner: Initial if reference is considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.